

CLAIMS

1. A ceramic substrate having a conductor layer formed
inside thereof or on the surface thereof,
5 wherein a notch is formed.
2. The ceramic substrate according to claim 1,
which has a resistance heating element formed inside
thereof or on the surface thereof; and functions as a hot
10 plate.
3. The ceramic substrate according to claim 1,
which has an electrostatic electrode formed inside
thereof; and functions as an electrostatic chuck.
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4. The ceramic substrate according to claim 1,
which has a chuck top conductor layer formed on the
surface thereof; has a guard electrode and/or a ground
electrode formed inside thereof; and functions as a wafer
20 prober.